

David V Tsu

List of Publications by Year in descending order

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29
papers

1,236
citations

687363

13
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610901

24
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all docs

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docs citations

29
times ranked

836
citing authors

#	ARTICLE	IF	CITATIONS
1	Effects of the nearest neighbors and the alloy matrix on SiH stretching vibrations in the amorphous SiO _x H (0 < x < 2) alloy system. <i>Physical Review B</i> , 1989, 40, 1795-1805.	3.2	396
2	Local atomic structure in thin films of silicon nitride and silicon diimide produced by remote plasma-enhanced chemical-vapor deposition. <i>Physical Review B</i> , 1986, 33, 7069-7076.	3.2	292
3	Effect of hydrogen dilution on the structure of amorphous silicon alloys. <i>Applied Physics Letters</i> , 1997, 71, 1317-1319.	3.3	247
4	Heterogeneity in hydrogenated silicon: Evidence for intermediately ordered chainlike objects. <i>Physical Review B</i> , 2001, 63, .	3.2	34
5	Reaction pathways and sources of OH groups in low temperature remote PECVD silicon dioxide thin films. <i>Journal of Electronic Materials</i> , 1990, 19, 209-217.	2.2	32
6	Obtaining optical constants of thin Ge _x Sb _y Te _z films from measurements of reflection and transmission. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 1999, 17, 1854-1860.	2.1	27
7	Formation of thin film dielectrics by remote plasma-enhanced chemical-vapor deposition (remote) Tj ETQq1 1 0.784314 rgBT /Overloc	6.1	24
8	Intervalenceband and plasmon optical absorption in heavily doped GaAs:C. <i>Journal of Applied Physics</i> , 2002, 91, 171.	2.5	24
9	Deposition of silicon-based dielectrics by remote plasma-enhanced chemical vapor deposition. <i>Journal of Crystal Growth</i> , 1988, 86, 804-814.	1.5	20
10	Infrared optical constants of silicon dioxide thin films by measurements of R and T. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 2000, 18, 1796.	1.6	19
11	Intermediate order in tetrahedrally coordinated silicon: evidence for chainlike objects. <i>Solar Energy Materials and Solar Cells</i> , 2003, 78, 115-141.	6.2	19
12	Mechanism of Properties of Noble ZnSâ€“SiO ₂ Protection Layer for Phase Change Optical Disk Media. <i>Japanese Journal of Applied Physics</i> , 2006, 45, 6294-6307.	1.5	19
13	Annealing study of the infrared absorption in an amorphous silicon dioxide film. <i>Journal of Non-Crystalline Solids</i> , 1989, 114, 459-461.	3.1	13
14	Low-temperature deposition of hydrogenated amorphous silicon (a-Si:H): Control of polyhydride incorporation and its effects on thin film properties. <i>Solar Cells</i> , 1989, 27, 121-136.	0.6	12
15	Deposition of silicon oxide, nitride and oxynitride thin films by remote plasma enhanced chemical vapor deposition. <i>Journal of Non-Crystalline Solids</i> , 1987, 90, 259-266.	3.1	11
16	Ion and neutral argon temperatures in electron cyclotron resonance plasmas by Doppler broadened emission spectroscopy. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 1995, 13, 935-942.	2.1	11
17	Oxidation studies of fluorine containing diamond films. <i>Applied Physics Letters</i> , 1991, 59, 745-747.	3.3	8
18	SiH stretching vibration in silicon suboxides: Local and remote induction effects. <i>Journal of Non-Crystalline Solids</i> , 1989, 114, 501-503.	3.1	7

#	ARTICLE	IF	CITATIONS
19	Optical measure of disorder: Why Urbach analysis works for amorphous silicon but fails for amorphous carbon. <i>Diamond and Related Materials</i> , 2020, 110, 108137.	3.9	4
20	Defects in a-Si:H films produced by remote plasma enhanced chemical vapor deposition. <i>Journal of Non-Crystalline Solids</i> , 1989, 107, 295-300.	3.1	3
21	<title>Low thermal budget optical recording: a method for higher recording densities</title>. , 2002, 4342, 124.		3
22	Development of transparent conductive oxide materials for improved back reflector performance for amorphous silicon based solar cells. <i>Materials Research Society Symposia Proceedings</i> , 2004, 808, 48.	0.1	3
23	Quantification of diffuse scattering in glass and polymers by parametric power law analysis of UV to NIR light. <i>Surface and Coatings Technology</i> , 2018, 336, 39-53.	4.8	3
24	Multichamber Integrated Deposition System For Silicon Based Dielectric Films. , 1989, , .		2
25	All optical broadband steering by phase angle controlled stationary element (PACSE) mirrors. , 2006, , .		1
26	Germanium: the good, the bad, and the ugly, howd-orbitalscan ruin materials or create new opportunities. <i>Waves in Random and Complex Media</i> , 2014, 24, 264-278.	2.7	1
27	Optical properties of Mo and amorphous MoOx, and application to antireflection coatings for metals. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2022, 40, 022209.	1.2	1
28	Photonic crystal nanosecond wavelength switches. , 2006, 6124, 79.		0
29	Use of Transparent Conductive Oxide Materials with Low Indices of Refraction in Amorphous Silicon-Based Solar Cell Technology. <i>Materials Research Society Symposia Proceedings</i> , 2005, 862, 2111.	0.1	0